FIGURE 1A

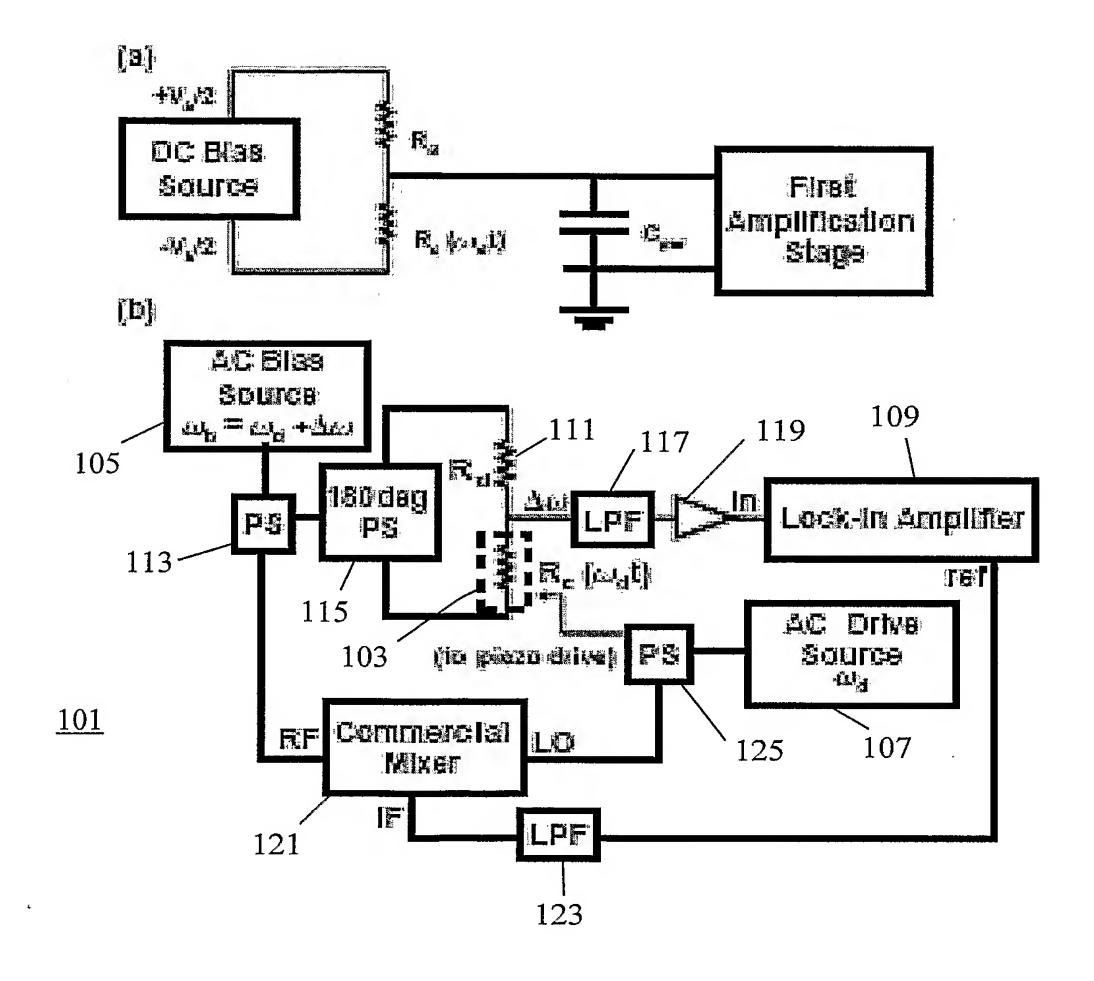


FIGURE 1B

FIGURE 2A

FIGURE 2B

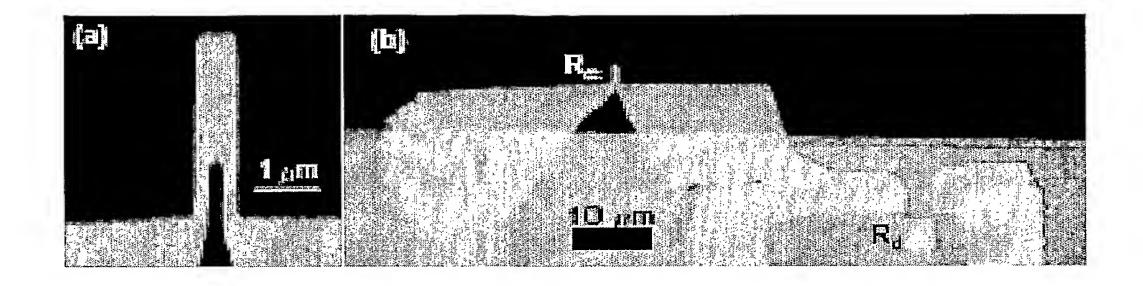


FIGURE 3A

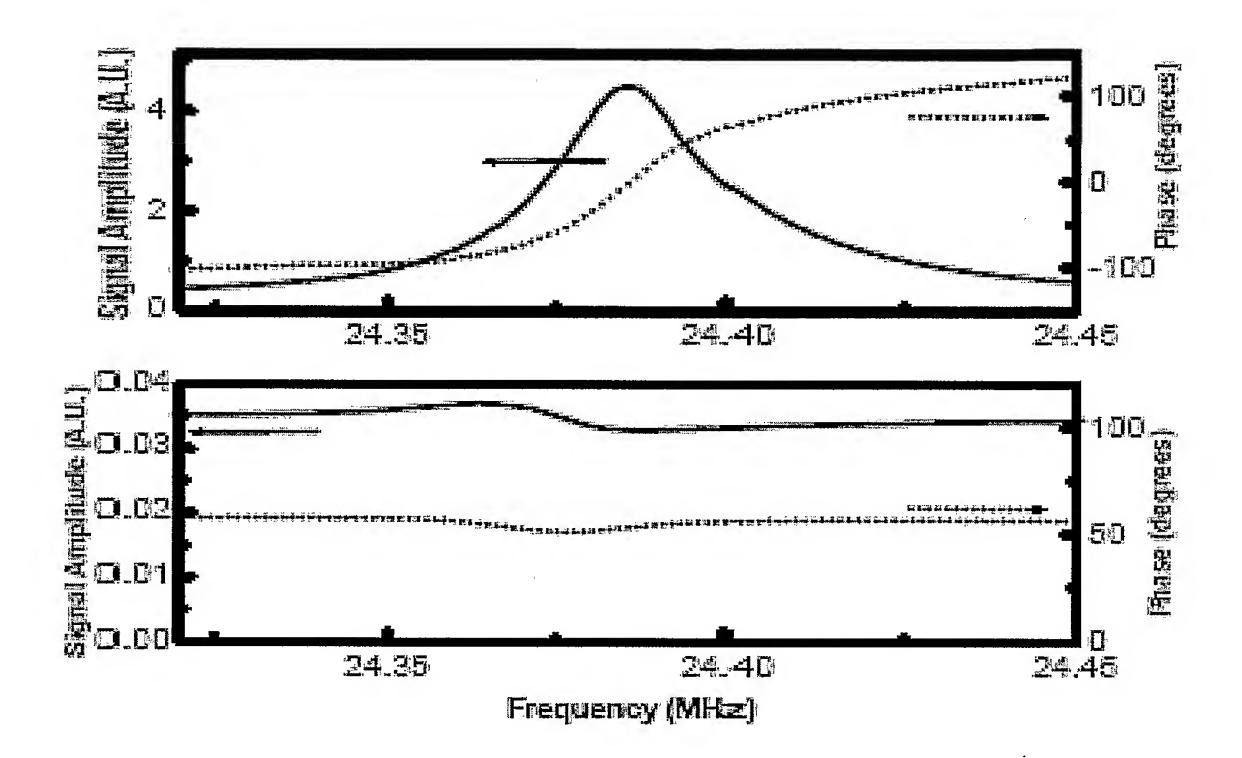
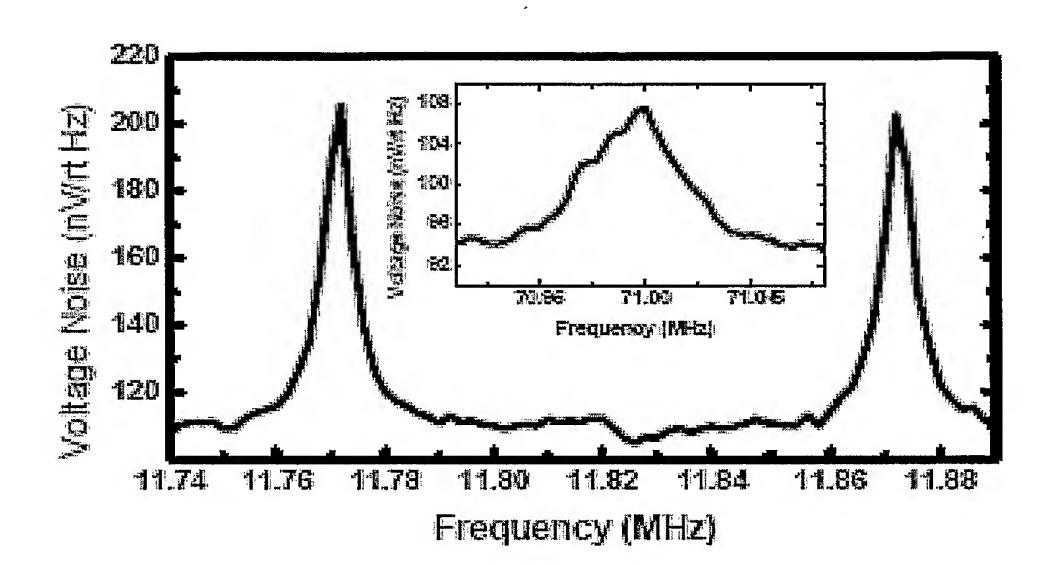


FIGURE 3B

FIGURE 4



5/16

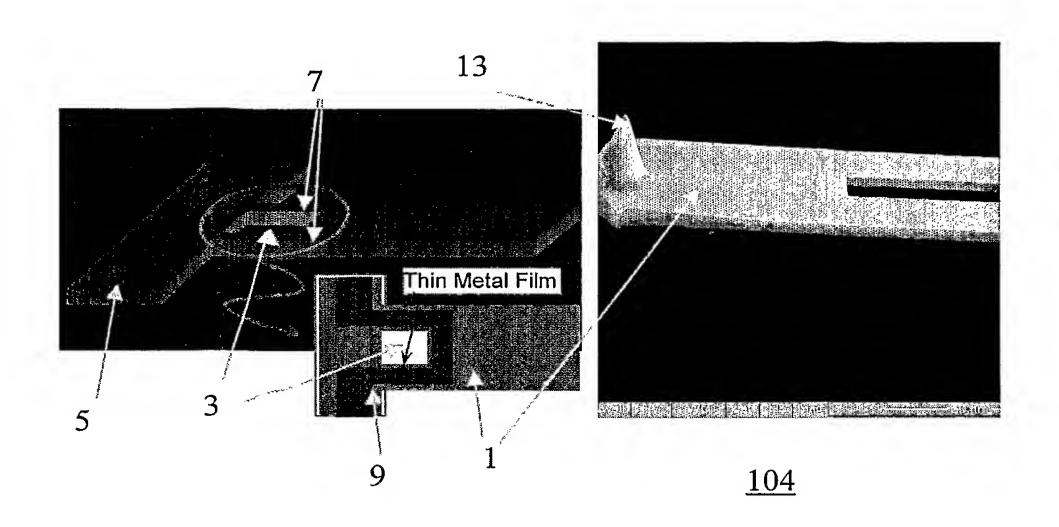


FIGURE 5a

FIGURE 5b

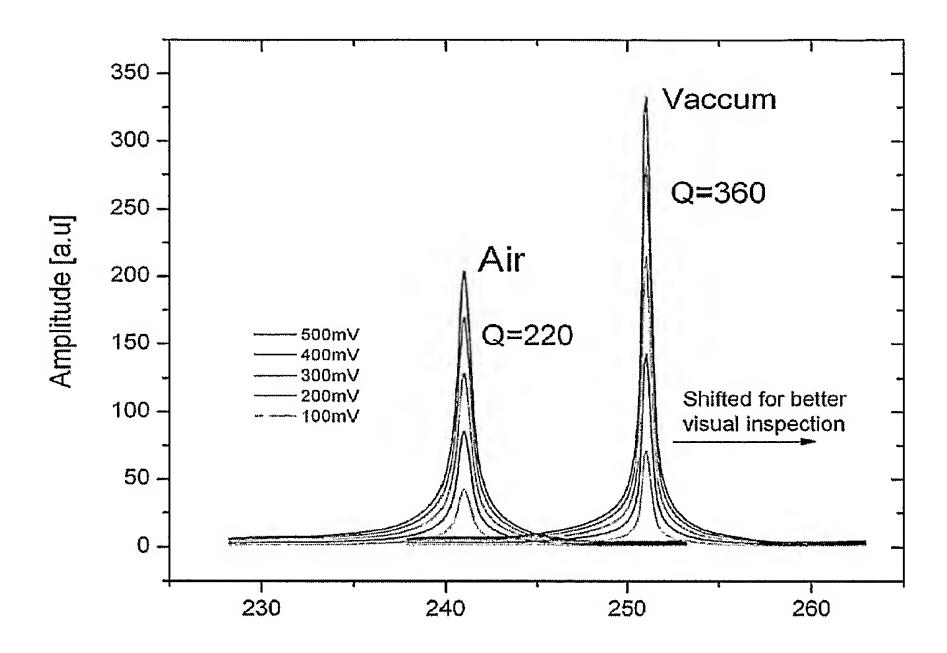


FIGURE 6

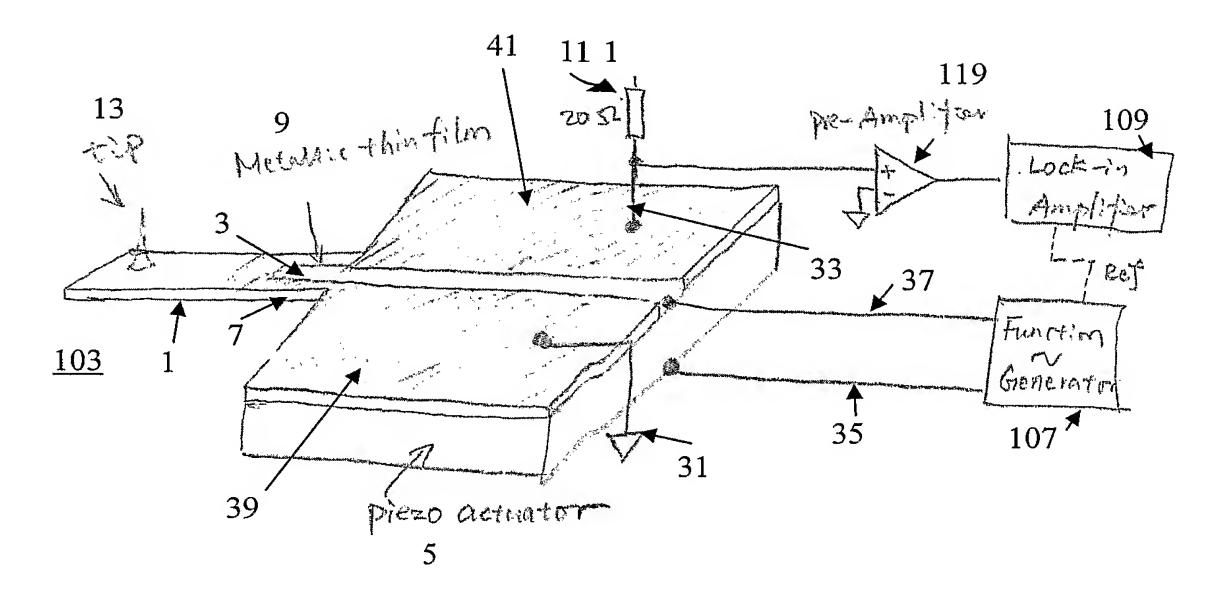
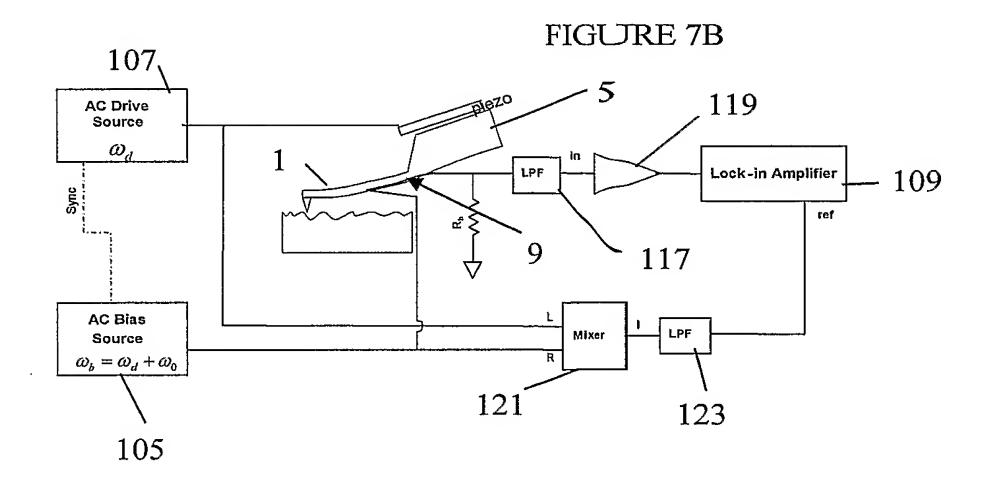


FIGURE 7A



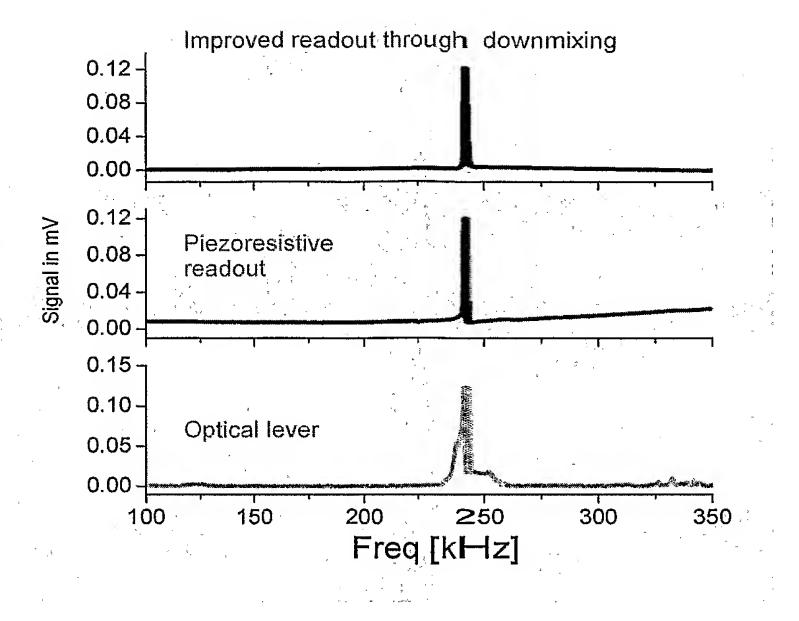


FIGURE 8

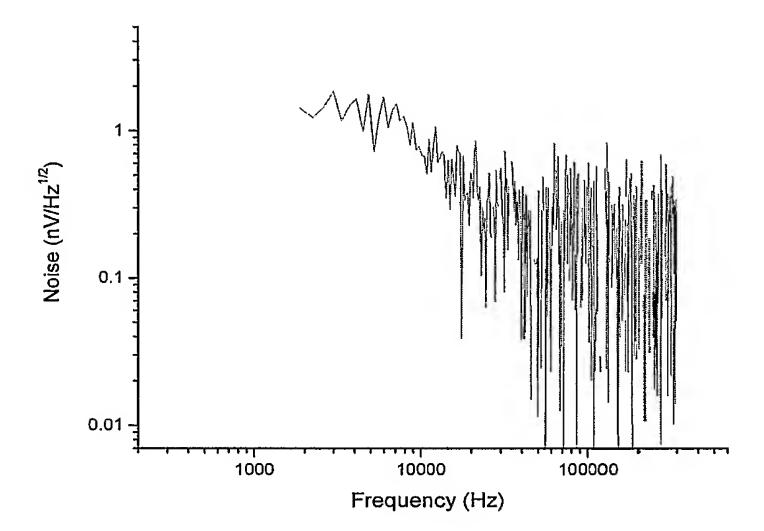
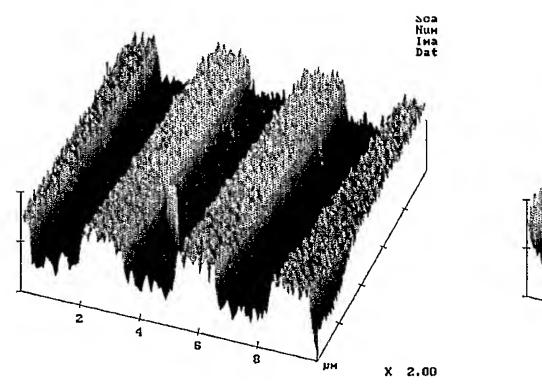


FIGURE 9



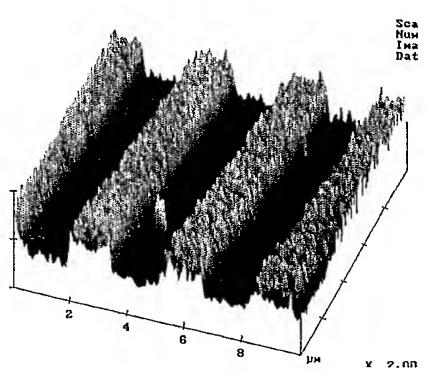
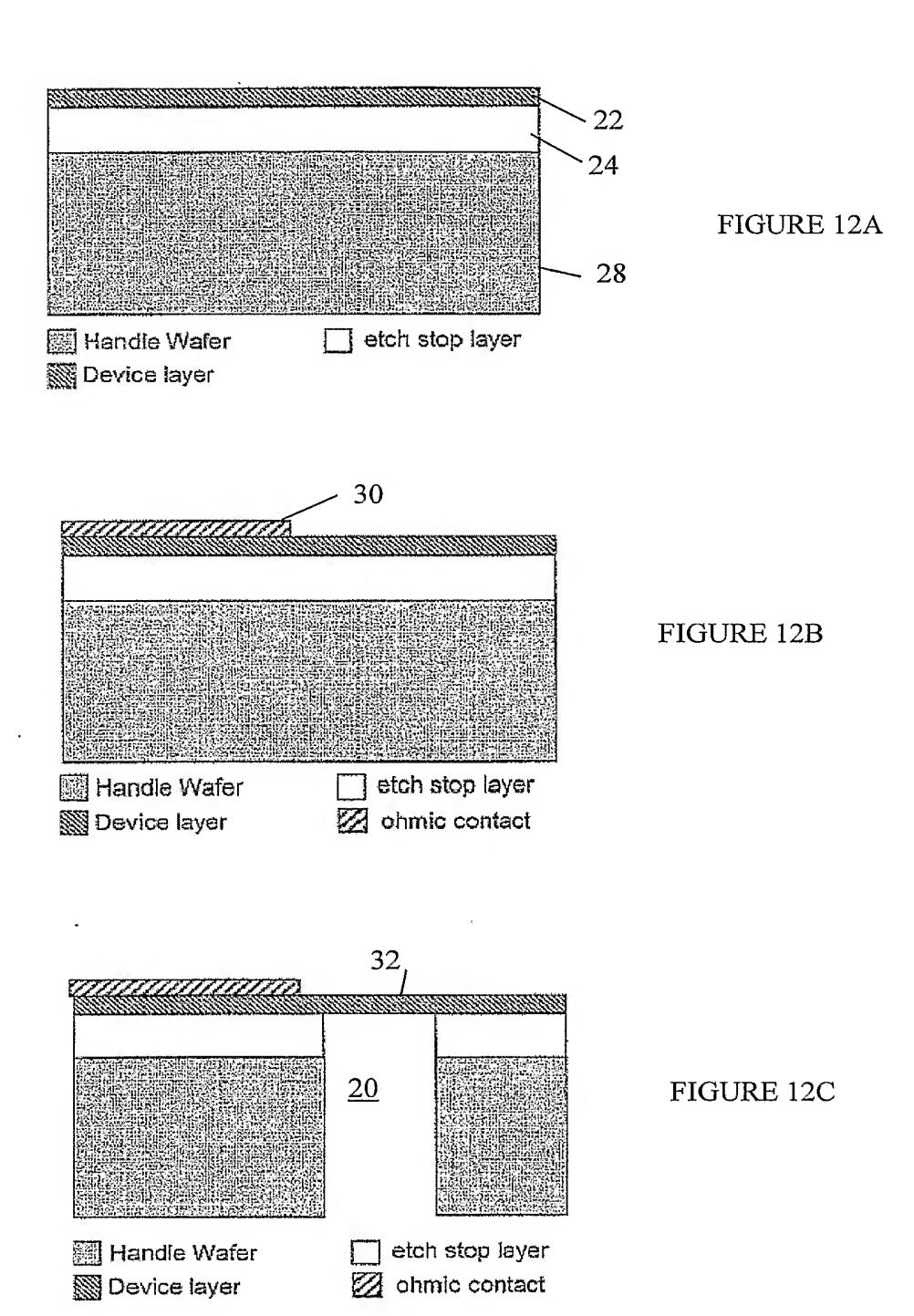


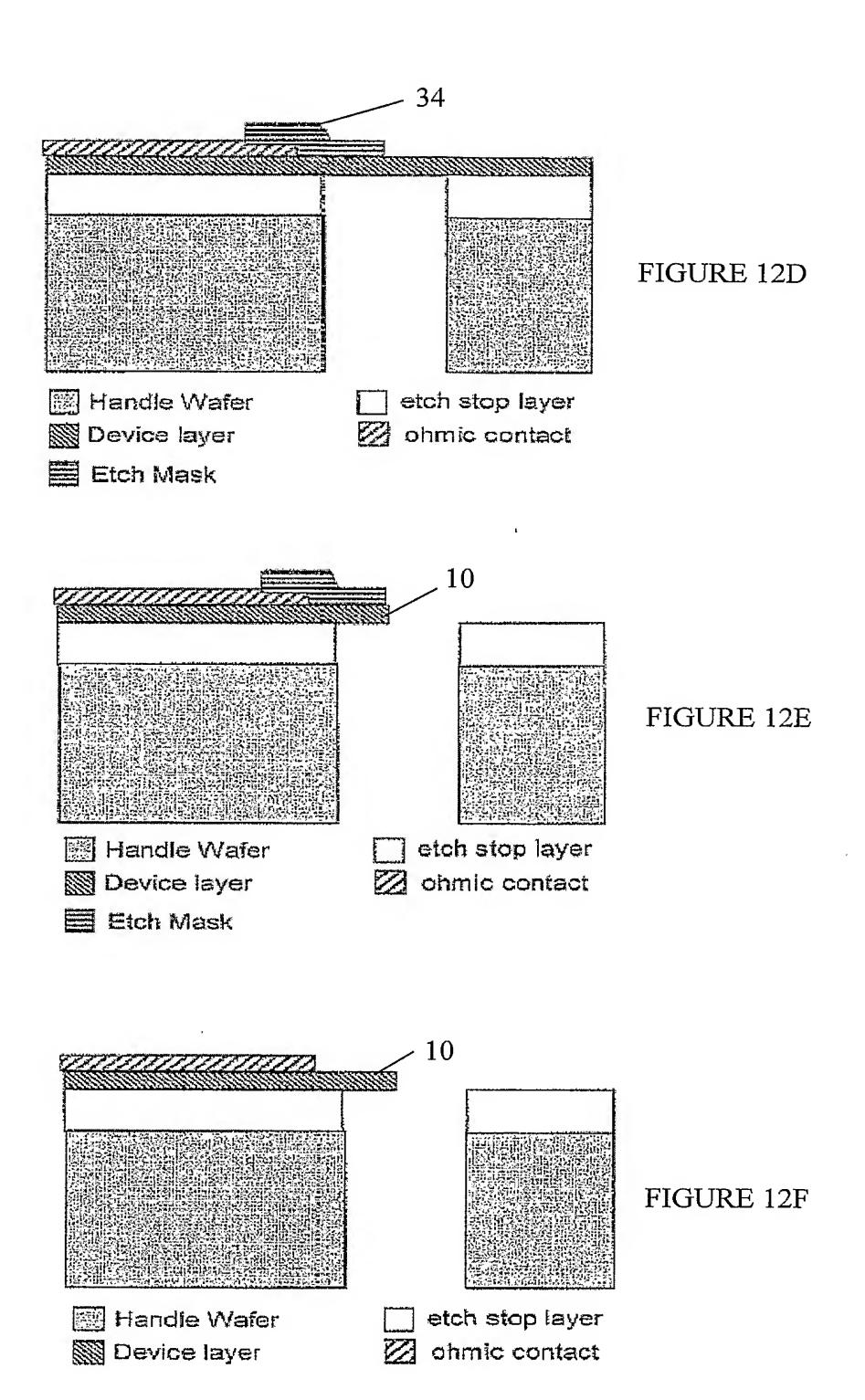
FIGURE 10A

FIGURE 10B

18	P-doped Siepilayer (30nm)	Device Layer
20 —	Undoped Silayer (80nm)	
20	SiO ₂ (400nm)	} Etch stop Layer
	Undoped Si (300-500μm)	Handle wafer 28

FIGURE 11





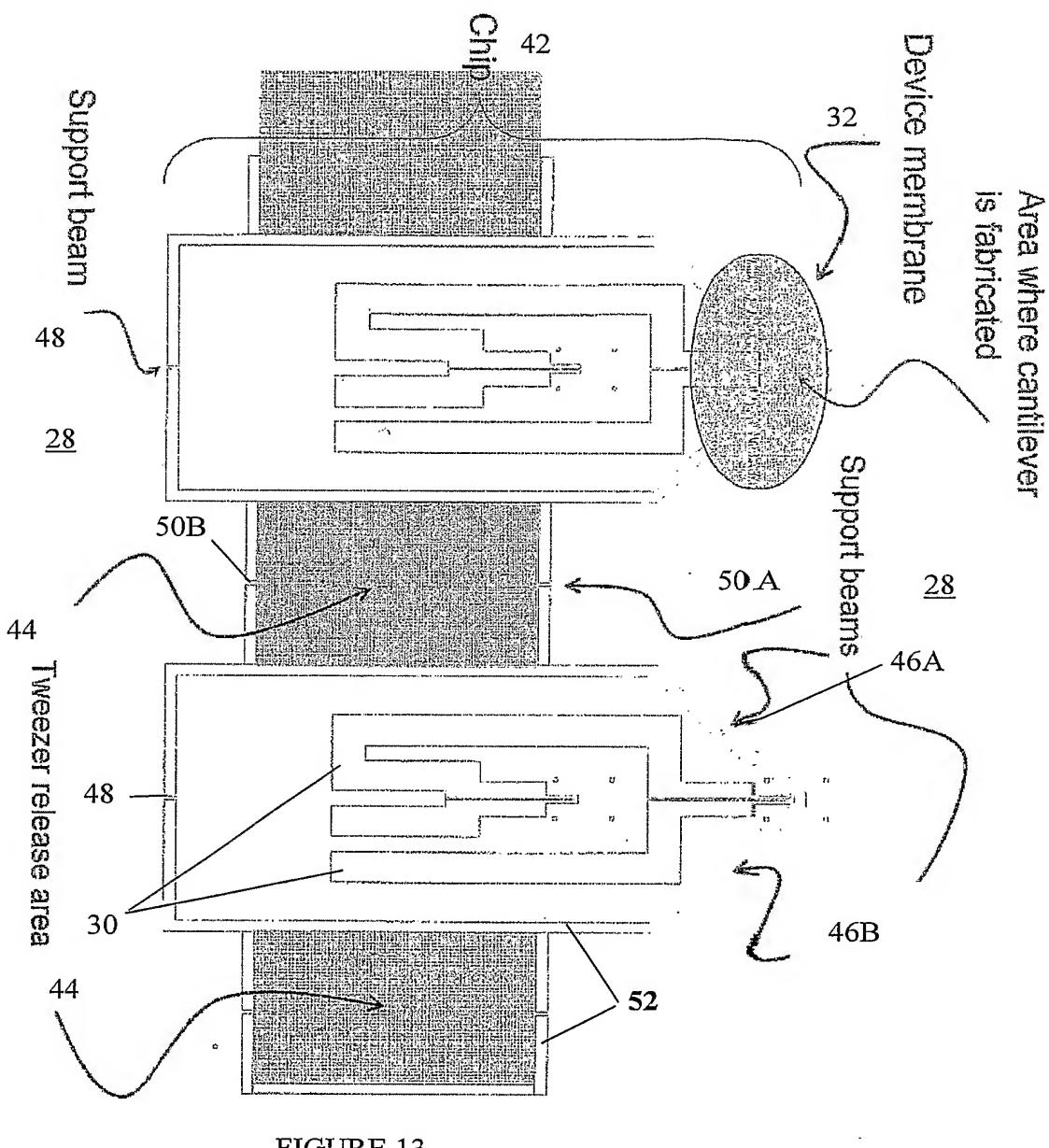


FIGURE 13

Top View: Fabricated cantilever in membrane

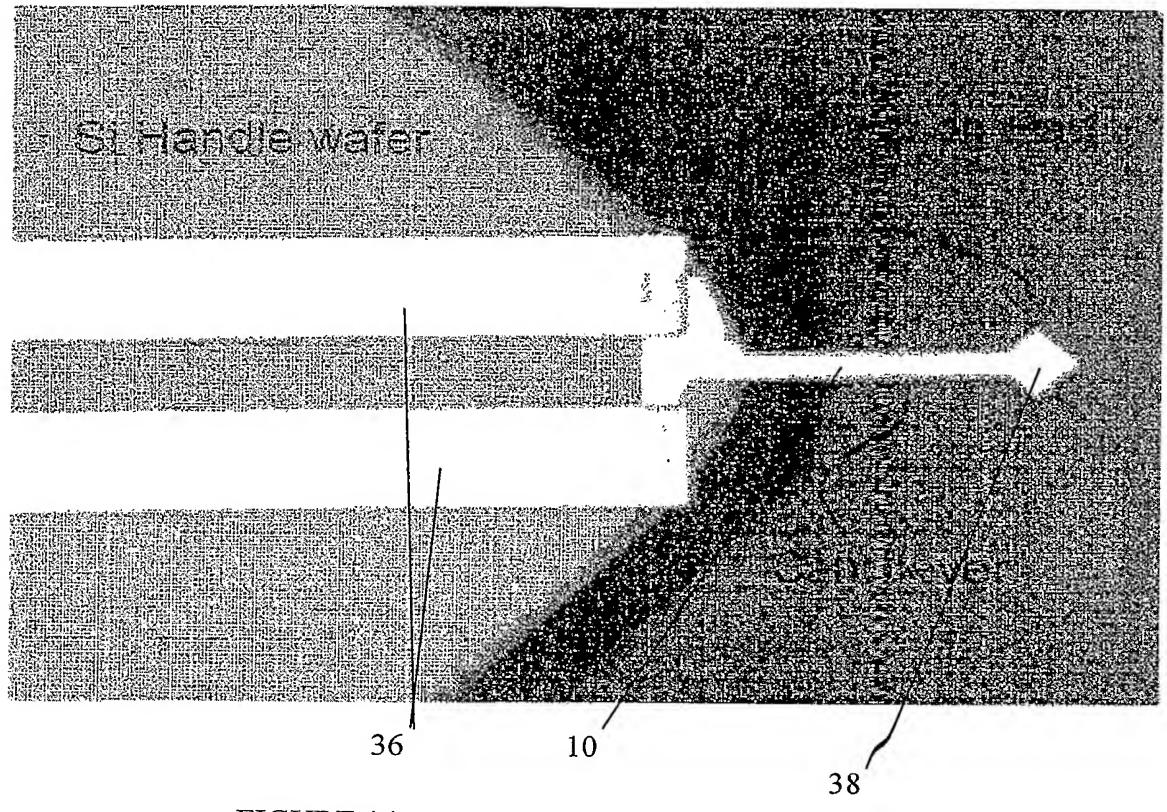
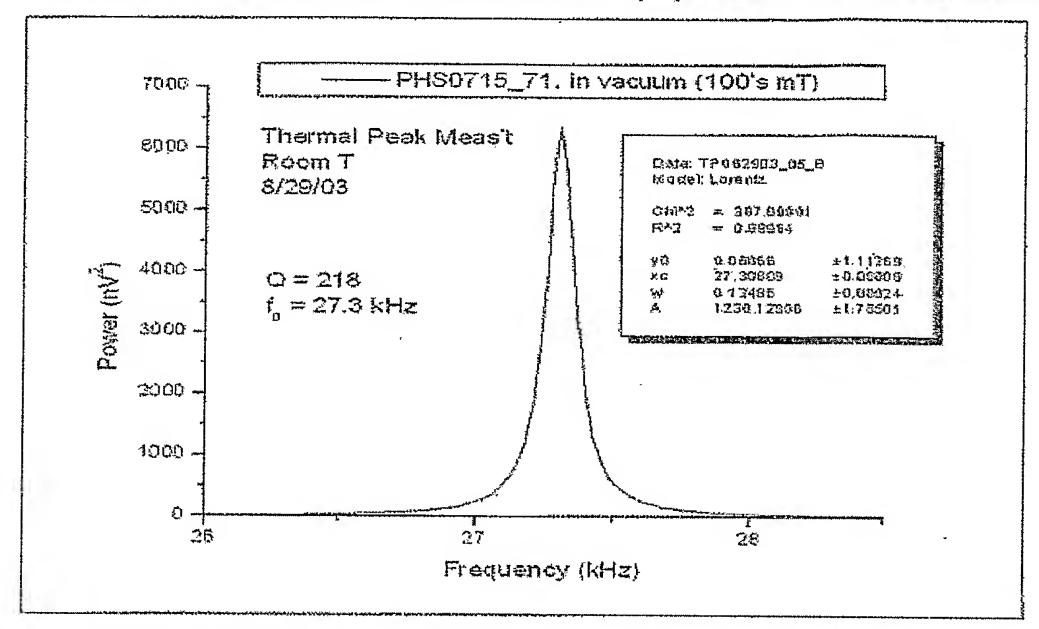


FIGURE 14

16/16

FIGURE 15

Thermally driven cantilever (optical transduction)



Thermally driven cantilever (piezoresistive transduction)

